	Туре	Ref #	Hits	Search Text	DBs
12	BRS	S25	808		US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
13	BRS	S26	38810	microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator	
14	BRS	S27	11 / 3480	beam same (first and second)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
15	BRS	S28		(335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator)	JPO; DERWENT;
16	BRS	S29		(beam same (first and second)) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator)	JPO; DERWENT;
17	BRS	S30	/1	((beam same (first and second)) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator)) and (335/78.ccls. 200/181.ccls.)	USPAT; EPO; JPO; DERWENT;

	Туре	Ref #	Hits	Search Text	DBs
18	BRS	S31	30917	heam with first and heam	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
19	BRS	S32	749	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and (beam with first and beam with second and beam with third)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
20	BRS	S33	13	((microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and (beam with first and beam with second and beam with third)) and (335/78.ccls. 200/181.ccls.)	US-PGPUB;
21	BRS	S34	290	((microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and (beam with first and beam with second and beam with third)) and electrostatic	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
22	BRS	S35	4	("6218911" "6307452").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
23	BRS	S36	7	"6218911".URPN.	USPAT
24	BRS	s37	5	("4740410" "5121089" "5168249" "5619061" "6020564").PN.	USPAT

	Туре	Ref #	Hits	Search Text	DBs
25	BRS	S38	38810		US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
26	BRS	S39		l(microelectromechanical or	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
27	BRS	S40	201	i	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
28	BRS	S41	13	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and airbridge	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
29	BRS	S45	41503	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator)	USPAT; EPO;
30	BRS	S46	843	335/78.ccls. 200/181.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
31	BRS	S47	72806	cantilever	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
32	BRS	S48	130	S45 and S46 and S47	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB

	Туре	Ref #	Hits	Search Text	DBs
33	BRS	S49	2081		US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
34	BRS	S50	1242		US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
35	BRS	S52	342	S50 and (recess recessed indentation groove)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
36	IS&R	S53	2	("6746891").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
37	BRS	S54	80981	(recess recessed indentation groove).clm.	US-PGPUB
38	BRS	S55	65334	electrode.clm.	US-PGPUB
39	BRS	S56	5167	S54 and S55	US-PGPUB
40	BRS	s57	2237	cantilever.clm.	US-PGPUB
41	BRS	S58	41	S56 and S57	US-PGPUB
42	BRS	S59	99656	(clearance gap space).clm.	US-PGPUB
43	BRS	S60	125520	substrate.clm.	US-PGPUB
44	BRS	S61	2841	S56 and S60	US-PGPUB
45	BRS	S62	643	S61 and S59	US-PGPUB
46	BRS	S63	40	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and S62	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB